| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|----------|------|--|---|---------------------|---------|------------------|
| 11 | 1537 | (257/290,291,292,294).CCLS. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | OFF | 2004/12/07 20:47 |
| L2 | 279 | I1 and silicon adj nitride | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2004/12/07 21:38 |
| L3 | 2487 | silicon adj nitride same plasma adj etching | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2004/12/07 20:51 |
| L4 | 7 | 12 and 13 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2004/12/07 20:51 |
| L5 | 92 | I2 and silicide | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2004/12/07 21:38 |